Title (en)

ALIGNER, DEVICE MANUFACTURING METHOD, MAINTENANCE METHOD AND ALIGNING METHOD

Title (de)

AUSRICHTUNGSVORRICHTUNG, BAUELEMENTEHERSTELLUNGSVERFAHREN, WARTUNGSVERFAHREN UND AUSRICHTUNGSVERFAHREN

Title (fr)

ALIGNEUR, PROCEDE DE FABRICATION DE DISPOSITIF, PROCEDE DE MAINTENANCE ET PROCEDE D ALIGNEMENT

Publication

EP 1724815 A4 20071024 (EN)

Application

EP 05709879 A 20050208

Priority

- JP 2005001827 W 20050208
- JP 2004033679 A 20040210

Abstract (en)

[origin: EP1724815A1] An exposure apparatus can prevent disadvantages of supplying liquid of reduced cleanliness and formation of watermarks. The exposure apparatus (EX) exposes a substrate (P) by irradiating exposure light (EL) onto the substrate (P) via a projection optical system (PL) and a liquid (LQ), and includes a liquid supply mechanism (10) for supplying the liquid (LQ), and a measuring device (60) which measures a time during which the supply of the liquid from the liquid supply mechanism is stopped (10).

IPC 8 full level

H01L 21/027 (2006.01); **G03F 7/20** (2006.01)

CPC (source: EP KR US)

G03F 7/2041 (2013.01 - KR); **G03F 7/70341** (2013.01 - EP KR US); **G03F 7/70716** (2013.01 - KR)

Citation (search report)

- [Y] WO 9949504 A1 19990930 - NIKON CORP [JP], et al
- [Y] US 2003136763 A1 20030724 - NAKAGAWA TOSHIMOTO [JP], et al
- [PA] WO 2004105107 A1 20041202 - NIKON CORP [JP], et al
- [A] US 2001019399 A1 20010906 - HAGIWARA SHIGERU [JP]
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EP1727188A4; EP3318928A1; WO2005081292A1; US8023100B2; US7804576B2; US8456608B2; US8891055B2

Designated contracting state (EPC)

AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HU IE IS IT LI LT LU MC NL PL PT RO SE SI SK TR

DOCDB simple family (publication)

EP 1724815 A1 20061122; **EP 1724815 A4 20071024**; **EP 1724815 B1 20120613**; EP 2256790 A2 20101201; EP 2256790 A3 20121010; JP 4548341 B2 20100922; JP WO2005076323 A1 20071018; KR 101166007 B1 20120717; KR 20070007280 A 20070115; US 2007159610 A1 20070712; US 2009244503 A1 20091001; US 7557900 B2 20090707; US 8115902 B2 20120214; WO 2005076323 A1 20050818

DOCDB simple family (application)

EP 05709879 A 20050208; EP 10177051 A 20050208; JP 2005001827 W 20050208; JP 2005517784 A 20050208; KR 20067015916 A 20050208; US 45724709 A 20090604; US 58814605 A 20050208